

ERRATA

Staff propose incorporation of the following amendments as part of the staff proposal:

The version of 2-1-128 shown here is the version that was discussed at the last workshop. Due to a clerical error in assembling the package for public notice, an older version was included instead. The discussion in the staff report describes the version presented here.

2-1-128 Exemption, Miscellaneous Equipment: The following equipment is exempt from the requirements of Sections 2-1-301 and 302, provided that the source does not require permitting pursuant to Section 2-1-319.

...

128.21 Modification, replacement, or addition of fugitive components (e.g. valves, flanges, pumps, compressors, relief valves, process drains) at existing permitted process units at petroleum refineries, chemical plants, bulk terminals or bulk plants, provided that the cumulative emissions from all additional components installed at a given process unit during any consecutive twelve month period do not exceed ~~the Best Available Control Technology trigger level in Reg. 2-2-304~~ 10 lb/day, and that the components meet applicable requirements of Regulation 8 rules.

...

Industry representatives requested that we add the phrase “beyond permitted levels” to the end of the new passage in 2-1-233. Staff believes that this clarifying language is consistent with the discussion in the staff report.

2-1-233 Alter: To make any physical change to, or change in the method of operation of, a source, which may affect emissions. Such changes require a permit to operate, and may require permit conditions, whether or not the alteration results in an emission increase. A change in process stream composition is not an alteration if the source’s description in the permit and permit conditions allow for the change in process stream composition, and the change does not increase emissions beyond permitted levels. The following activities are specifically identified as “alterations.”

233.1 Replacement of burners with non-identical burners.

233.2 Maintenance of glass furnaces involving component replacement, unless all replacements are with identical components.

233.3 Expansion of the physical boundaries of a semiconductor fabrication area.

(Adopted May 17, 2000)